L Number	Hits	Search Text	DB	Time stamp
-	2	("4717445").PN.	USPAT;	2004/06/23 16:20
	-		US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	50	(monitoring or control) with (etch\$4 adj bias)	USPAT;	2004/06/23 16:21
-		(Montoring of control) with (closion and blas)	US-PGPUB;	2004/00/20 10:21
	1		EPO; JPO;	
			DERWENT;	
1	ļ			
	10	//manitaring or control) with (atabas a di bias)) and coloulated	IBM_TDB	0004/06/02 46:00
-	10	((monitoring or control) with (etch\$4 adj bias)) and calculat\$4	USPAT;	2004/06/23 16:22
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	6	(((monitoring or control) with (etch\$4 adj bias)) and	USPAT;	2004/06/24 09:50
		calculat\$4) and capacit\$4	US-PGPUB;	
1			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	6	(((monitoring or control) with (etch\$4 adj bias)) and	USPAT;	2004/06/24 11:58
		calculat\$4) and capacit\$4	US-PGPUB	
-		, , , , , , , , , , , , , , , , , , , ,	EPO; JPO;	
		·	DERWENT;	
			IBM_TDB	
_	140	measur\$4 with capacit\$5 with cathode with anode	USPAT;	2004/06/24 14:20
	''	modelity i wan supusites with cathods with allocs	US-PGPUB;	2004/00/24 14.20
			EPO; JPO;	
			DERWENT:	
	0	(maggur@4 with consoit@5 with acthodo with anada) and	IBM_TDB	0004/06/04 40:00
-	١	(measur\$4 with capacit\$5 with cathode with anode) and	USPAT;	2004/06/24 12:09
		((secong adj2 anode) with (second cathode))	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
	1003	managur@4 same conscit@E same cathode come and	IBM_TDB	0004/00/04 40:00
ļ -	1003	measur\$4 same capacit\$5 same cathode same anode	USPAT;	2004/06/24 12:09
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
		(m	IBM_TDB	
-	310	(measur\$4 same capacit\$5 same cathode same anode) and	USPAT;	2004/06/24 12:10
		(second with cathode)	US-PGPUB;	
			EPO; JPO;	
		•	DERWENT;	
	:		IBM_TDB	
-	0	((measur\$4 same capacit\$5 same cathode same anode) and	USPAT;	2004/06/24 12:10
		(second with cathode)) and ((secong adj2 anode) with	US-PGPUB;	
		(second cathode))	EPO; JPO;	
]			DERWENT;	
		·	IBM_TDB	
-	94	(measur\$4 same capacit\$5 same cathode same anode) and	USPAT;	2004/06/24 13:21
		(second adj3 cathode)	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	20	(measur\$4 same capacit\$5 same cathode same anode) and	USPAT;	2004/06/24 12:11
		(second adj cathode)	US-PGPUB;	
		· · · · · · · · · · · · · · · · · · ·	EPO; JPO;	
	ļ		DERWENT;	
			IBM_TDB	

Continue			· · · · · · · · · · · · · · · · · · ·	,	,
- 296 ((measur\$4 same capacit\$5 same cathode same anode) and (second adj cathode) with (second adj anode))) and calcul\$6 (measur\$4 same capacit\$5 same cathode same anode) and calcul\$6 ((measur\$4 same capacit\$5 same cathode same anode) and calcul\$6 ((measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 ((measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 ((measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and (second adj4 same capacit\$5 same cathode same anode) and (second adj same) and (se	-	6	(measur\$4 same capacit\$5 same cathode same anode) and	USPAT;	2004/06/24 14:12
DERWENT; IBM TDB USPAT; US-PGPUB; EPO, JPO; DERWENT; IBM TDB U		Ì	((second adj cathode) with (second adj anode))	,	
-	1				
USPAT; U					
Continue				IBM_TDB	
- 296 (measur\$4 same capacit\$5 same cathode same anode) and calcul\$6 (measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 (measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 (etch\$4 adj bias) and (unit with area with capacit\$5) - 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 485 (etch\$4 adj bias) and (unit with area with capacit\$5) - 5 (etch\$4 adj bias) and (unit with area with capacit\$5) - 6 (measur\$4 same capacit\$5 same cathode same anode) and (second adj cathode) with (second adj anode)) and (test near3 apparatus) - 7 (etch\$4 adj bias) and (test near3 apparatus) - 8 (etch\$4 adj bias) and (test near3 apparatus) - 9 (etch\$4 adj bias) and (test near3 apparatus) - 10 (etch\$4 adj bias) and apparatus - 11 (etch\$4 adj bias) and apparatus - 12 (etch\$4 adj bias) and apparatus - 13 (etch\$4 adj bias) and apparatus - 14 (etch\$4 adj bias) and apparatus - 15 (etch\$4 adj bias) and apparatus - 16 (etch\$4 adj bias) and apparatus - 17 (etch\$4 adj bias) and apparatus - 18 (etch\$4 adj bias) and apparatus - 19 (etch\$4 adj bias) and apparatus - 19 (etch\$4 adj bias) and apparatus - 10 (etch\$4 adj bias) and apparatus	-	0	((measur\$4 same capacit\$5 same cathode same anode) and	USPAT;	2004/06/24 13:20
- 296 (measur\$4 same capacit\$5 same cathode same anode) and calcul\$6 (measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 (measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 (measur\$4 adj bias (etch\$4 adj bias) and (unit with area with capacit\$5) (measur\$4 same capacit\$5 same cathode same anode) and (second adj bias) and (unit with area with capacit\$5) (measur\$4 same capacit\$5 same cathode same anode) and (second adj cathode) with (second adj anode)) and (test near3 apparatus) (measur\$4 same capacit\$5 same cathode same anode) and (second adj cathode) with (second adj anode)) and (test near3 apparatus) (second adj cathode) with (second adj anode)) and (test near3 apparatus) (second adj cathode) with (second adj anode)) and (test near3 apparatus) (second adj cathode) (second adj anode)) and (test near3 apparatus) (second adj cathode) (second adj anode)) (second adj anode)) (second adj cathode) (second adj anode)) (second adj cathode) (second adj anode)) (second adj cathode) (second adj cathode) (second adj anode)) (second adj cathode) (second adj cathode) (second adj anode)) (second adj cathode) (second adj cathode) (second adj cathode) (second adj cathode) (second adj anode)) (second adj cathode) (second adj cathode) (second adj cathode) (second adj cathode) (second adj anode)) (second adj cathode) (second adj cathode) (second adj anode)) (second adj cathode) (second adj anode)) (second adj cathode) (second adj anode)) (second adj cathode) (second adj			((second adj cathode) with (second adj anode))) and calcul\$6	US-PGPUB;	
BM_TDB	İ			EPO; JPO;	
Content Cont				DERWENT;	
Calcul\$6				IBM_TDB	
Calcul\$6	-	296	(measur\$4 same capacit\$5 same cathode same anode) and	USPAT;	2004/06/24 13:22
- 34 ((measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 - 485 etch\$4 adj bias - 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode)) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 2 161 (etch\$4 adj bias) and apparatus - 3 2 (measur\$4 with capacit\$5 with cathode with anode) and (second adj anode)) and (second adj anode) and (second adj anode)) and (second adj anode) and (second adj anode)) and (second adj anode) anode) and (second adj				US-PGPUB;	
- 485 ((measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 - 485 etch\$4 adj bias - 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode)) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 1 (etch\$4 adj bias) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus					
- 485 ((measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 - 485 etch\$4 adj bias - 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and apparatus - 1 (etch\$4 adj bias) and apparatus - 2004/06/24 13:25 2004/06/24 14:13 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:20 2004/06/24 14:20 2004/06/24 14:20					
- 485 (measur\$4 same capacit\$5 same cathode same anode) and (second adj3 cathode)) and calcul\$6 - 485 etch\$4 adj bias - 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 0 (measur\$4 same capacit\$5 same cathode same anode) and (second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and apparatus - 1 (etch\$4 adj bias) and apparatus - 2004/06/24 13:22 2004/06/24 13:25 2004/06/24 13:25 2004/06/24 13:25 2004/06/24 13:25 2004/06/24 13:25 2004/06/24 13:25 2004/06/24 13:25 2004/06/24 13:25 2004/06/24 13:41 2004/06/24 14:13 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:20 2004/06/24 14:20 2004/06/24 14:20				1	
Second adj3 cathode) and calcul\$6	_	34	((measur\$4 same capacit\$5 same cathode same anode) and	_	2004/06/24 13:22
- 485 etch\$4 adj bias - 485 etch\$4 adj bias - 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 161 (etch\$4 adj bias) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus					
- 485 etch\$4 adj bias etch\$4 adj bias 2004/06/24 13:25 SPGPUB EPC JPC DERWENT IBM_TDB USPAT US-PGPUB EPC JPC DERWENT IBM_TDB US-PGPUB EPC JPC DERWENT US-PGPUB TECH		Ì	(
- 485 etch\$4 adj bias (etch\$4 adj bias) and (unit with area with capacit\$5) (etch\$4 adj bias) and (unit with area with capacit\$5) (etch\$4 adj bias) and (unit with area with capacit\$5) (measur\$4 same capacit\$5 same cathode same anode) and (second adj cathode) with (second adj anode)) and (test near3 apparatus) (etch\$4 adj bias) and (test near3 apparatus) (etch\$4 adj bias) and (test near3 apparatus) (etch\$4 adj bias) and apparatus (etch\$4 adj bias) and etchode with anode) and apparatus (etch\$4 adj bias) and etchode with anode) and apparatus (etch\$4 adj bias) and etchode with anode) and apparatus (etch\$4 adj bias) and etchode with anode) and apparatus (etch\$4 adj bias) and etchode with anode) and apparatus (etch\$4 adj bias) and etchode with anode) and apparatus (etch\$4 adj bias) and etchode with anode) and apparatus (etch\$4 adj bias) and etchode with anode) and apparatus			,		
- 485 etch\$4 adj bias				1	
- 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and apparatus - 161 (etch\$4 adj bias) and apparatus - 161 (etch\$4 adj bias) and apparatus - 162 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 162 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 163 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 164 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus	1_	485	etch\$4 adi hias	_	2004/06/24 13:25
- 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 161 (etch\$4 adj bias) and apparatus - 162 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 162 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 163 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 164 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 166 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 167 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 168 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 169 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 169 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 160 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 160 (measur\$4 with capacit\$5 with cathode with anode) and apparatus		700	Cichipa auj bias		2004/00/24 13.23
- 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 0 (measur\$4 same capacit\$5 same cathode same anode) and (second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and apparatus - 161 (etch\$4 adj bias) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 63 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 64 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 65 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 65 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 66 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 67 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 68 (measur\$4 with capacit\$5 with cathode with anode) and apparatus					
- 3 (etch\$4 adj bias) and (unit with area with capacit\$5) - 0 (measur\$4 same capacit\$5 same cathode same anode) and (second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and apparatus - 161 (etch\$4 adj bias) and apparatus - 2004/06/24 14:13 2004/06/24 14:13 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:20 2004/06/24 14:20 2004/06/24 14:20 2004/06/24 14:20					
- 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 1 (etch\$4 adj bias) and apparatus - 161 (etch\$4 adj bias) and apparatus - 162 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 162 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 163 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 164 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 166 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 167 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 168 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 169 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 160 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 160 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 160 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 160 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 160 (measur\$4 with capacit\$5 with cathode with anode) and apparatus				1	
- 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 161 (etch\$4 adj bias) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus		ء ا	(stob\$4 adi hisa) and (unit with area with conscit®E)		0004/06/04 40:44
- 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) 1 (etch\$4 adj bias) and (test near3 apparatus) 2004/06/24 14:13 2004/06/24 14:13 2004/06/24 14:13 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:18 2004/06/24 14:20 2004/06/24 14:20	-	3	(etch\$4 adj blas) and (unit with area with capacit\$5)		2004/06/24 13:44
- 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 161 (etch\$4 adj bias) and apparatus - 161 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 162 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 163 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 164 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 166 (measur\$4 with capacit\$5 with cathode with anode) and apparatus	1				
- 0 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) - 1 (etch\$4 adj bias) and (test near3 apparatus) - 161 (etch\$4 adj bias) and apparatus - 161 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 162 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 163 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 164 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 166 (measur\$4 with capacit\$5 with cathode with anode) and apparatus		ŀ			
- 10 (measur\$4 same capacit\$5 same cathode same anode) and ((second adj cathode) with (second adj anode)) and (test near3 apparatus) 1 (etch\$4 adj bias) and (test near3 apparatus) 1 (etch\$4 adj bias) and apparatus 2 (etch\$4 adj bias) and apparatus 3 (etch\$4 adj bias) and apparatus 4 (etch\$4 adj bias) and apparatus 5 (etch\$4 adj bias) and apparatus 6 (etch\$4 adj bias) and apparatus 7 (etch\$4 adj bias) and apparatus 8 (etch\$4 adj bias) and apparatus 9 (etch\$4 adj bias) and apparatus 9 (etch\$4 adj bias) and apparatus 10 (etch\$4 adj bias)					
((second adj cathode) with (second adj anode)) and (test near3 apparatus) 1 (etch\$4 adj bias) and (test near3 apparatus) 1 (etch\$4 adj bias) and apparatus) 1 (etch\$4 adj bias) and apparatus 2 (etch\$4 adj bias) and apparatus 3 (etch\$4 adj bias) and apparatus 4 (etch\$4 adj bias) and apparatus 5 (etch\$4 adj bias) and apparatus 6 (etch\$4 adj bias) and apparatus 8 (etch\$4 adj bias) and apparatus 9 (etch\$4 adj bias) and apparatus 9 (etch\$4 adj bias) and apparatus 9 (etch\$4 adj bias) and apparatus 1 (etch\$4 adj bias) and apparatus 2 (etch\$4 adj bias) and apparatu			105		
rear3 apparatus) EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; ISPO; JPO; DERWENT; J	-	0			2004/06/24 14:13
- 11 (etch\$4 adj bias) and (test near3 apparatus) - 161 (etch\$4 adj bias) and apparatus - 161 (etch\$4 adj bias) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 63 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 64 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 65 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 65 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 67 (measur\$4 with capacit\$5 with cathode with anode) and apparatus		ļ		1	
- 161 (etch\$4 adj bias) and (test near3 apparatus) - 161 (etch\$4 adj bias) and apparatus - 161 (etch\$4 adj bias) and apparatus - 162 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 163 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 164 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 165 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 166 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 167 (measur\$4 with capacit\$5 with cathode with anode) and apparatus			near3 apparatus)		
- 161 (etch\$4 adj bias) and (test near3 apparatus) - 161 (etch\$4 adj bias) and apparatus - 161 (etch\$4 adj bias) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus - 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus					
- 161 (etch\$4 adj bias) and apparatus (etch\$4 adj bias) and apparatus (etch\$4 adj bias) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus			() () () () () () () ()		
- 161 (etch\$4 adj bias) and apparatus (etch\$4 adj bias) and apparatus (etch\$4 adj bias) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; US-PGPUB; EPO; JPO; DERWENT;	-] 1	(etcn\$4 adj bias) and (test near3 apparatus)		2004/06/24 14:18
- 161 (etch\$4 adj bias) and apparatus (etch\$4 adj bias) and apparatus (etch\$4 adj bias) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus					
- 161 (etch\$4 adj bias) and apparatus (etch\$4 adj bias) and apparatus (etch\$4 adj bias) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus					
- 161 (etch\$4 adj bias) and apparatus USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DSPAT; US-PGPUB; EPO; JPO; DERWENT; Apparatus 2004/06/24 14:18					
- 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; DERWENT;					
- 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and apparatus EPO; JPO; DERWENT; US-PGPUB; EPO; JPO; DERWENT;	-	161	(etch\$4 adj bias) and apparatus	USPAT;	2004/06/24 14:18
- 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT;					
- 62 (measur\$4 with capacit\$5 with cathode with anode) and apparatus (measur\$4 with capacit\$5 with cathode with anode) and uS-PGPUB; EPO; JPO; DERWENT;	1				
- 62 (measur\$4 with capacit\$5 with cathode with anode) and USPAT; US-PGPUB; EPO; JPO; DERWENT;	1			DERWENT;	
apparatus US-PGPUB; EPO; JPO; DERWENT;				IBM_TDB	
apparatus US-PGPUB; EPO; JPO; DERWENT;	-	62	(measur\$4 with capacit\$5 with cathode with anode) and	USPAT;	2004/06/24 14:20
EPO; JPO; DERWENT;			apparatus	US-PGPUB;	
DERWENT;					